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United States Patent [19] Turner

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[54] OFF-AXIS INTERFACE FOR A MASS SPECTROMETER

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250/396 R

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[57] ABSTRACT

A mass spectrometer for analyzing a beam of ions generated from a sample of analyze comprises an analyzer (3) and an interface between the analyze sample (1) and the analyzer. The inlet aperture to the analyzer (13) is positioned off the axis of the ion beam (2) exiting the interface system, and a deflector is (14) provided to generate an electric field between the interface system and the analyzer to deflect the ion beam into the inlet aperture of the analyzer.

4 Claims, 2 Drawing Sheets

